

## Special Issue

# Metrology in Times of Digitization

### Message from the Guest Editor

The adoption of digital technology in the world of metrology and calibration has been accelerating in recent years. The traditional paperwork of making manual records of measurements, typing and signing certificates is being replaced by their digital counterparts. Additionally, the recording of environmental conditions, original measurement data and much more—if not all—of the documentation required in the ISO 17025 is saved on hard disks instead of binders in cupboards, or even in the cloud. In the technology aspect there is the parallel development of big data, the application of data mining and artificial intelligence. In 2022, metrology day is dedicated to this subject, especially regarding the concept that data must be “FAIR”, an acronym that stands for findable, accessible, interoperable and reusable. *Metrology* will dedicate a Special Issue to this subject, where authors are invited submit contributions that focus on any of these or related aspects of metrology.

- metrology 4.0
- big data
- open source
- digitization
- data mining

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### Guest Editor

Prof. Dr. Han Haitjema

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### Deadline for manuscript submissions

closed (31 October 2022)



## Metrology

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## About the Journal

### Message from the Editor-in-Chief

*Metrology* draws together researchers from diverse areas of metrology or measurement technology in a wide variety of applications. I encourage you to submit your manuscripts for consideration or publication in the area of measurement engineering, according to the scope of the journal. *Metrology* is supported by our authors and their institutes through low article processing charges (APC) for accepted papers. We hope you will support the journal by becoming one of our authors.

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### Editor-in-Chief

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